

Appl. No. 10/660,715  
Amendment dated: April 30, 2009  
Reply to OA of: January 26, 2009

This listing of claims will replace all prior versions and listings of claims in the application.

**Listing of Claims:**

1(currently amended). A vertical sublimation apparatus, comprising:  
a sublimation channel body;  
a material rack for storing materials that will be evaporated;  
a heating evaporation device surrounding an evaporation pipe to control heating temperatures according to different materials for evaporating said materials;  
a vapor channel for transporting said evaporated materials into said sublimation channel body;  
a vapor channel incubating device surrounding said vapor channel for maintaining the temperature of said vapor channel;  
a condensation device surrounding the upper part of said sublimation channel body for controlling condensation temperatures required by different evaporated materials;  
a product incubating device for maintaining the temperature of end products;  
~~an incubating device for maintaining the temperatures of both the vapor channel and end products;~~ and  
a product scratching device;  
wherein said heating evaporation device, said vapor channel, said condensation device, ~~[[and]] said incubating device~~ said vapor channel incubating device and said product incubating device are individually configured.

2(previously presented). The vertical sublimation apparatus as claimed in claim 1, wherein the structure of said material rack comprises a plurality of rails and fixed rings, and said rails are fixed by two fixed rings and located in said evaporation pipe for storing materials ready to be evaporated.

3(currently amended). The vertical sublimation apparatus as claimed in claim 1, wherein ~~said incubating device comprises a vapor channel incubating device and a product incubating device, and said vapor channel incubating device surrounds an outlet port of said vapor channel to maintain the temperature of the sublimated vapor and transports said sublimated vapor continuously into said sublimation channel body.~~

4(original). The vertical sublimation apparatus as claimed in claim 3, wherein said product incubating device surrounds the lower part of said sublimation channel body to avoid accumulation of said sublimated vapor.

5(original). The vertical sublimation apparatus as claimed in claim 1, wherein said product scratching device comprises a central axis for shifting up and down and/or rotating said product scratching device, fixed rings, central support and sawtooth.

6(original). The vertical sublimation apparatus as claimed in claim 5, wherein said sawtooth is located near said fixed rings beneath said central support for scratching off condensed products from the wall of said sublimation channel body.

7(original). The vertical sublimation apparatus as claimed in claim 1, wherein said lower part of said sublimation channel body is formed as a product storage tank for collecting said condensed products falling therein after being scratched off by said scratching device.

8(original). The vertical sublimation apparatus as claimed in claim 1, further comprising heat shield devices made of quartz wool and located at two ends of said sublimation channel body with one end of said evaporation pipe being further away from said sublimation channel body for maintaining a certain temperature inside said sublimation apparatus.

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9(previously presented). The vertical sublimation apparatus as claimed in claim 1, further comprising sealing caps located at each end of said channels with heat shield devices placed therein and locked by O-rings to prevent leakage.

Claims 10-12(canceled).

13(withdrawn-Previously presented). A vapor collection device, comprising:  
a collecting bottle filled with wires for expanding the contacting surface between vapor and cold surface;  
an inlet pipe for connecting with said vacuum sublimation purification apparatus, so the uncondensed vapor can be guided into said collecting bottle; and  
an exhaust pipe for connecting with said vacuum extraction system.

14(withdrawn). The vapor collection device as claimed in claim 13, wherein said vapor collection device is disposed between said sublimation channel body and said vacuum system for condensing said uncondensed vapor via low temperature, thus preventing said vacuum pump from being contaminated.

15(withdrawn-Previously presented). A vacuum sublimation purification process applied to said vertical sublimation purification apparatus of claim 1,comprising the following steps:

placing materials on said material rack;  
turning on said vacuum extraction device to vacuum;  
turning on said heating evaporation device to achieve the required sublimation temperature of materials;  
turning on all incubating devices to maintain the condensation temperature;  
scratching and collecting products at a regular time interval during the evaporation process; and

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cooling down the temperature after evaporation is completed and take taking out products from said product storage tank.

16(withdrawn). The vacuum sublimation purification process as claimed in claim 15, wherein conditions of sublimation required for purifying Alq<sub>3</sub> are: evaporation temperature being 350~450°C, condensation temperature being 250~350°C, evaporation temperature being 50~100°C higher than condensation temperature, and system pressure being 0.1~1 10<sup>-6</sup> mbar.

17(withdrawn). The vacuum sublimation purification process as claimed in claim 15, wherein conditions of sublimation for purifying NPB are: evaporation temperature being 250~350°C, condensation temperature being 150~250°C, evaporation temperature being 30~80°C higher than condensation temperature, and system pressure being 0.1~1 10<sup>-6</sup> mbar.

18(withdrawn). The vacuum sublimation purification process as claimed in claim 15, wherein conditions of sublimation for purifying CuPc are: evaporation temperature being 500~650°C, condensation temperature being 400~500°C, evaporation temperature being 50~100°C higher than condensation temperature, and system pressure being 0.1~1 10<sup>-6</sup> mbar.

19(withdrawn-previous presented). A vacuum sublimation purification process applied to said horizontal sublimation purification apparatus of claim 10, comprising following steps:

placing materials in said material carrier;  
placing said material carrier at said center of said sublimation channel body;  
tightening up and seal said two end pipes;  
turning on said vacuum device to vacuum;

turning on said heating evaporation device to control said temperature between said center and said two ends of said sublimation channel body; and

cooling down said temperature and relieving said vacuum after evaporation is completed, then scratching and collecting products.

20(withdrawn). The vacuum sublimation purification process as claimed in claim 16, wherein conditions of sublimation for purifying Alq<sub>3</sub> are: evaporation temperature being 350~450°C, condensation temperature being 250~350°C, evaporation temperature being 50~100°C higher than condensation temperature, and system pressure being 1~1 10<sup>-6</sup> mbar.

21(withdrawn). The vacuum sublimation purification process as claimed in claim 16, wherein conditions of sublimation for purifying NPB are: evaporation temperature being 250~350°C, condensation temperature being 150~250°C, evaporation temperature being 30~80°C higher than condensation temperature, and system pressure being 0.1~1 10<sup>-6</sup> mbar.

22(withdrawn). The vacuum sublimation purification process as claimed in claim 16, wherein conditions of sublimation for purifying CuPc are: evaporation temperature being 500~650°C, condensation temperature being 400~500°C, evaporation temperature being 50~100°C higher than condensation temperature, and system pressure being 0.1~1 10<sup>-6</sup> mbar.